

Attorney Docket No. 033082 M 275



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Kazuhide HASEBE, et al. Confirmation No.: 6774
U.S. Serial No. : 10/552,262
Filed : October 5, 2005
Examiner : Lan Vinh
Group Art. Unit : 1792
For : SILICON DIOXIDE FILM REMOVING METHOD AND
PROCESSING SYSTEM

**RESPONSE AS "SUBMISSION" UNDER 37 C.F.R. 1.114
WITH REQUEST FOR CONTINUED EXAMINATION**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

MAIL STOP: RCE

Sir:

In response the Advisory Action mailed on August 11, 2008, for which the time for response is set to expire October 25, 2008, please amend the above-identified application as set forth below and consider the following remarks. Also enclosed is a Petition for a 3 month Extension of Time with requisite fees as well as a Request for Continued Examination with requisite fee.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 5 of this paper.